

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:	)	Confirmation No. 9528
Koichiro TANAKA	)	
Application No. 10/769,820	)	Examiner: Samuel Heinrich
Filed: February 3, 2004	)	Group Art Unit: 1725
For: LASER IRRADIATION STAGE, LASER	)	
IRRADIATION OPTICAL SYSTEM, LASER	)	
IRRADIATION APPARATUS, LASER	)	
IRRADIATION METHOD, AND METHOD OF	)	
MANUFACTURING A SEMICONDUCTOR	)	Date: November 8, 2006
DEVICE	)	

**AMENDMENT**

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed August 8, 2006, please amend the above-identified patent application as follows:

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 7 of this paper.